JUN 2 0 2006

PATENT Customer No. 22,852 Attorney Docket No. 04329.2959-01

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re A	Application of:	)	
Gaku Minamihaba et al.		)	Group Art Unit: 1765
Application No.: 10/762,514		.)	Examiner: Chen, Eric Brice
Filed:	January 23, 2004	)	Confirmation No. 5239
For:	SLURRY FOR CHEMICAL MECHANICAL POLISHING OF COPPER AND METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE USING THE SLURRY	)	
P.O. B	nissioner for Patents Box 1450 ndria, VA 22313-1450		·
Sir:			

## **AMENDMENT**

In reply to the Office Action mailed March 21, 2006, with a period for response extending through June 21, 2006, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks begin on page 4 of this paper.

Attachment to this Paper: Declaration Under 37 C.F.R. 1.132